

Notice of References Cited

Application/Control No.

10/799,892

Applicant(s)/Patent Under
Reexamination
KAUFFMAN ET AL.

Examiner

Scott L. Jarrett

Art Unit

3623

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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.

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